

Appl. No. 10/009,910
 Amdt. Dated September 22, 2004
 Reply to Office Action of June 24, 2004

Attorney Docket No. 81839.0107

Customer No. 26021

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Makoto IIDA et al.

Serial No.: 10/009,910

Confirmation No.: 7347

Filed: December 12, 2001

For: SILICON WAFER, SILICON
 EPITAXIAL WAFER, ANNEAL
 WAFER AND METHOD FOR
 PRODUCING THEM

Art Unit: 1765

Examiner: Matthew J. Song

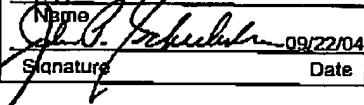
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September 22, 2004

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 23,009

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09/22/04

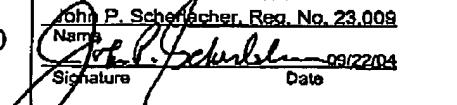
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RESPONSE TO FINAL OFFICE ACTION

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Dear Sir:

I hereby certify that this paper and every paper referred to herein is being transmitted via facsimile to recipient at (703) 872-9306 on:
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In response to the Final Office Action of June 24, 2004, please enter and consider the following Remarks/Arguments:

The Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.